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INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)		APPLICANT Pearlstein, et al.	
		FILING DATE August 18, 2000	GROUP 3753

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U.S. PATENT DOCUMENTS

EXAM- INER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPRO- PRIATE
GW	5 9 3 7 8 9 5	8/17/99	LeFebre, et al	137	494	4/17/98
	6 0 4 5 1 1 5	4/4/00	Martin, Jr., et al	251	118	4/17/98
	4 7 4 4 2 2 1	5/17/88	Karl O. Knollmueller	62	48	6/29/87
	5 5 1 8 5 2 8	5/21/96	Tom, et al	95	103	10/13/94
	5 7 0 4 9 6 5	1/6/98	Tom et al	95	95	5/20/96
	5 7 0 4 9 6 7	1/6/98	Tom, et al	96	143	5/20/96
	5 7 0 7 4 2 4	1/13/98	Tom, et al	95	95	11/1/96
	5 4 0 9 5 2 6	4/25/95	Zheng, et al	96	132	10/5/93
	6 0 2 7 5 4 7	2/22/00	Tom, et al	95	96	5/18/98
GW	6 0 8 9 0 2 7	7/18/00	Wang, et al	62	46.1	4/28/99

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
GW	9 9 0 9 1 3 7	2/25/99	WO	C12M	3/00	X	
	0 9 1 6 8 9 1	5/19/99	EP	F17C	13/04	X	
GW	0 9 1 6 8 9 1	8/9/99	EP	F17C	13/04	X	

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

GW	"A New Era In Gas Handling Safety: Sub-Atmospheric..." McManus, JV, et al, Semiconductor Fabtech.
GW	"Sub-Atmospheric Pressure Gas Delivery System For Chemical." Donatucci, et al, IBM Microelectronics Div.
	"Reducing the HPM Risk: Pressure-actuated Gas Delivery", Olander, et al, Semiconductor Fabtech.

EXAMINER <i>George Walton</i>	DATE CONSIDERED <i>9/29/01</i>
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EXAMINER: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

H. Kern
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 4/11/2001